



2800

2800

2881

0430

PATENT APPLICATION

RECEIVED
APR 11 2002
TECHNICAL
5817-03

#2/Submission
of
Declaration

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takua NAKAMURA

Application No.: 10/080,712

Filed: February 25, 2002

Docket No.: 111856

For: METHOD FOR ASSESSING IRRADIATION INTENSITY OF A LASER BEAM, AN
APPARATUS FOR ASSESSING IRRADIATION INTENSITY USED UNDER THIS
METHOD, AND A LASER BEAM IRRADIATION SYSTEM

SUBMISSION OF ORIGINAL DECLARATION

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Submitted herewith is the original signed Declaration of the Inventor. This
Declaration corresponds to the facsimile copy of the Declaration filed on February 25, 2002.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

Thomas J. Pardini
Registration No. 30,411

JAO:TJP/zmc

Date: March 15, 2002

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

RECEIVED
MAY 14 2002
TC 2800 MAIL ROOM